

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Atsushi TAKAKUWA et al.

Application No.: New U.S. Patent Application

Filed: January 12, 2004

Docket No.: 118315

For: DEVICE MANUFACTURING METHOD AND DEVICE, ELECTRO-OPTIC DEVICE,
AND ELECTRONIC EQUIPMENT

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. Relevance of the English and non-English language references 1, 4, 5 are discussed in the present specification.
- ☒ 3. The present application was filed or entered the U.S. National Stage of the PCT after June 30, 2003. In accordance with the June 11, 2003, Notice waiving the requirements of 37 C.F.R. §1.98(a)(2)(i), copies of any U.S. patents and patent application publications are not attached.
- ☒ 4. English-language Abstracts of the non-English language references 2-12 are attached hereto.
- ☒ 5. A computer-generated English translation of the following Japanese Patent Publication has been obtained from the website of the Japanese Patent Office ([<http://www.jpo.go.jp>]), and is attached, but has not been reviewed for accuracy. See Reference 2-12.

Respectfully submitted,



James A. Oliff

Registration No. 27,075

Thomas J. Pardini

Registration No. 30,411

JAO:TJP/smk

Date: January 12, 2004

OLIFF & BERRIDGE, PLC

P.O. Box 19928

Alexandria, Virginia 22320

Telephone: (703) 836-6400

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					Sheet	1	of	1
Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 118315		APPLICATION NO. New U.S. Patent Application		
INFORMATION DISCLOSURE STATEMENT								
(Use several sheets if necessary)				APPLICANTS Atsushi TAKAKUWA et al.				
				FILING DATE January 12, 2004				
U.S. PATENT DOCUMENTS								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME		CLASS	SUB CLASS	
	1	6,057,067	5/2/2000	ISBERG et al.				
FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY		CLASS	SUB CLASS	
	2	JP A 10-125929 w/ Abst & Trans	5/15/1998	Japan				
	3	JP A 10-125930 w/ Abst & Trans	5/15/1998	Japan				
	4	JP A 10-125931 w/ Abst & Trans	5/15/1998	Japan				
	5	JP A 11-26733 w/ Abst & Trans	1/29/1999	Japan				
	6	JP A 2000-133809 w/ Abst & Trans	5/12/2000	Japan				
	7	JP A 2001-51296 w/ Abst & Trans	2/23/2001	Japan				
	8	JP A 2001-125138 w/ Abst & Trans	5/11/2001	Japan				
	9	JP A 2002-217390 w/ Abst & Trans	8/2/2002	Japan				
	10	JP A 2002-217391 w/ Abst & Trans	8/2/2002	Japan				
	11	JP A 2003-031778 w/ Abst & Trans	1/31/2003	Japan				
	12	JP A 2003-142666 w/ Abst & Trans	5/16/2003	Japan				
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)								
	13	Tatsuya SHIMODA et al., "Surface Free Technology by Laser Annealing (SUFTLA)", 1999, IEEE, Pgs., IEDM 99-289-292						
	14	Sumio UTSUNOMIYA et al., "Low-temperature poly-Si TFT transferred onto plastic substrates by using surface free technology by laser ablation/annealing (SUFTLA [®])", Journal of the SID, 2002, Pgs., 69-73						
	15	S. UTSUNOMIYA et al., "Low Temperature Poly-Si TFT-LCD Transferred onto Plastic Substrate Using Surface Free Technology by laser Ablation/Annealing (SUFTLA [®])", Asia Display, 2001, Pgs. 339-342						
	16	Akihiko ASANO et al., "Low-Temperature Polycrystalline-Silicon TFT Color LCD Panel Made of Plastic Substrates", SID, 2002, Pgs. 1196-1199						
	17	M. KIMURA et al., "An area-ratio gray-scale method to achieve image uniformity in TFT-LEPDs", Journal of the SID, 2000, Pgs. 97						
	18	Sumio UTSUNOMIYA et al., "Flexible TFT-LEPD Transferred onto Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA [®])", Europdisplay, 2002, Pgs., 79-82						
	19	T. SHIMODA et al., "Technology for Active Matrix Light Emitting Polymer Displays", IEEE 1999, Pgs., IEDM 99-107-110						
	20	S. UTSUNOMIYA et al., "Flexible Color AM-OLED Display Fabricated Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA [®]), and Ink-jet Printing Technology", SID, 2003, Pgs., 864-867						
EXAMINER					DATE CONSIDERED			
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

Date: January 12, 2004